

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Dipankar Chandra, et al.
Filing Date: November 13, 2001
Title: SENSOR FOR DETECTING SMALL
CONCENTRATIONS OF A TARGET MATTER

Assistant Commissioner
For Patents and Trademarks
Washington, DC 20231


Dear Sir:

INFORMATION DISCLOSURE STATEMENT

Applicants respectfully request, pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98, that the references listed on the attached PTO-1449 form be considered and cited in the examination of the above-identified application. Copies of these references are enclosed for the convenience of the Examiner. Furthermore, pursuant to 37 C.F.R. § 1.97(g) and (h), no representation is made that these references are material to patentability of the present application or that a search has been made.

Respectfully submitted,

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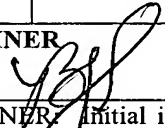
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| PTO-1449 | | Application No. | | Applicant(s) Dipankar (nmi) Chandra, et al. | | | |
| Information Disclosure Citation in an Application | | Docket Number 004578.1148 | | Group Art Unit | | Filing Date | |

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| EXAMINER  | | DATE CONSIDERED 9/29/2003 |
| EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant. | | |

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